

Inventor: T. L. Gilton  
Title: Switchable Circuit Devices  
Assignee: Micron Technology, Inc.

**INFORMATION DISCLOSURE STATEMENT**

**PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98**

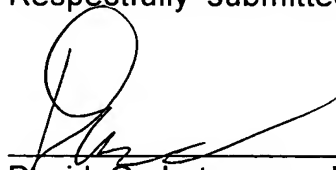
In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a divisional application of co-pending application Serial No. 10/177,242, filed June 21, 2002. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 10/23/03

By:   
David G. Latwesen, Ph.D.  
Reg. No. 38,533

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2428		priority SERIAL NO. 10/177,242	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT T. L. Gilton			
				priority FILING DATE June 21, 2002		priority GROUP 2812	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,187,604 B1	2/13/01	Gilton			
	AB						
	AC						
	AD						
	AE						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes      No
	AM						
	AN						
	AO						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR		Anodic Oxidation of Porous Silicon Layers Formed on Lightly p-Doped Substrates; A. Bsiesy et al; pp. 3450-3456; J. Electrochem. Soc. Vol 138, No. 11; November 1991; The Electrochemical Society, Inc.				
	AS		Information and Properties of Porous Silicon Film; Yoshinobu Arita and Yoshio Sunohara; Journal of the Electrochemical Society; Vol. 124, No. 2; February 1977; pp. 285-295				
			Building from the Bottom Up; Nano Technology; October 16, 2000; C & EN; pg. 27-32				
			New Tools for Tiny Jobs; Nano Technology; October 16, 2000; C & EN; pg. 33-35				
			Firms Find a New Field of Dreams; Nano Technology; October 16, 2000; C & EN; pg. 36-38				
	AT		Crafting a National Nanotechnology Effort; Nano Technology; October 16, 2000; C & EN; pg. 39-42				
EXAMINER				DATE CONSIDERED			
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>							